

In re Patent Application of

Confirmation No. 2949

SASAKI

Allowed:

December 19, 2003

Serial No. 09/487,259

Atty Ref.:

1035-243

Filed: January 19, 2000

Group:

2814

For: METHOD FOR MANUFACTURING A

SEMICONDUCTOR DEVICE BY PARTIALLY

DICING A SUBSTRATE AND SUBSEQUENT

CHEMICAL ETCHING

Examiner:

A. Mai

February 25, 2004

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

COMMENTS ON EXAMINER'S STATEMENT OF REASONS FOR ALLOWANCE

Sir:

The Examiner's Statement of Reasons for Allowance refers to a "protective holder having radically-extending grooves ..." The statement should refer to --radially-extending grooves--. Applicant traverses the Examiner's reasons for allowance to the extent these reasons are inconsistent with, add or omit claim limitations.

Respectfully submitted,

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